



500.39826CX1/E5828-04EU

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Seiichiro KANNO *et al.*  
Serial No. : 10/679,342  
Filed : 7 October 2003  
For : SEMICONDUCTOR MANUFACTURING APPARATUS AND  
METHOD OF PROCESSING SEMICONDUCTOR WAFER  
USING PLASMA, AND WAFER VOLTAGE PROBE  
Group : 1763  
Examiner : Unknown  
Conf. No : 2653

**INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR §1.97(b)**

Commissioner for Patents  
POB 1450  
Alexandria, Virginia 22313-1450

13 January 2005

Sir:

In the matter of the above-identified application, Applicant hereby submits the attached information under 37 CFR §§1.97 and 1.98 for entry and consideration by the Office, and for printing on the first page of any patent issuing hereon, as listed on the accompanying Form PTO-1449 Equivalent.

In accordance with the Final Rule under 37 CFR §1.98 effective 21 October 2004, no copies of US patents/published applications are submitted herewith.

Additionally, no separate concise explanation of relevance is submitted for each item of information not in the English language In accordance with 37 CFR §1.98(3) because an English language Abstract for each of the references also is attached.

This IDS is timely filed under 37 CFR §1.97(b) prior to mailing of a first Action on the merits in the present case. Applicant submits that all requirements under 37 CFR §§1.97 and 1.98 are complete, and respectfully requests the Examiner to return an initialed copy of the attached Form PTO-1449 Equivalent to indicate entry and consideration of the listed information.

Respectfully submitted,



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Attachments:  
PTO-1449  
3 JP References/English Abstracts

Form PTO-1449  
EquivalentU.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DKT. NO.  
500.49826CX1SERIAL NO.  
10/679,342INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT

(Use several sheets if necessary)

## APPLICANT

Seiichiro KANNO *et al.*

## FILING DATE

7 October 2003

## GROUP

1763

## U.S. PATENT DOCUMENTS

Ex. Initial	Doc. No.	Date	Name	Class	Subclass	Filing Date
AA	5,534,070	07/09/1996	Okamura <i>et al.</i>			
AB						
AC						
AD						
AE						
AF						
AG						
AH						

## U.S. PATENT APPLICATIONS

	Publication Number	Name	Publication Date
AI			
AJ			
AK			
AL			

## FOREIGN PATENT DOCUMENTS

	Doc. No.	Date	Country	Class	Subclass	Translation/Abstract?	
						Yes	No
AM	06-287760	10/11/1995	JP			Abstract	
AN	09-129594	05/16/1997	JP			Abstract	
AO	11-167997	06/22/1999	JP			Abstract	
AP							
AQ							

## OTHER DOCUMENTS

AR	
AS	
AT	

Examiner

Date Considered